

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:

Docket No.: 2771-594-CIP

Applicants: WANG, Ziyun, et al.

Conf. No.: 1841

Application No.: 10/699,079

Art Unit: 1621

Date Filed: October 31, 2003

Examiner: Samuel A. Barts

Title: COMPOSITION AND METHOD FOR LOW TEMPERATURE DEPOSITION OF SILICON-CONTAINING FILMS

Customer No.:

23448

CERTIFICATE OF EFS FILING

I hereby certify that this document is being filed via EFS in the United States Patent and Trademark Office on **June 7, 2008**.

/Steven J. Hultquist/

RESPONSE TO APRIL 18, 2008 OFFICE ACTION AND FILING OF REQUEST FOR EXAMINATION UNDER 37 CFR 1.114 IN U.S. PATENT APPLICATION NO. 10/699,079

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

This responds to the April 18, 2008 Office Action in the above-identified application. In view of the finality of the Office Action, a Request for Continued Examination is concurrently being filed with this response, to ensure substantive consideration of the amendments made herein.

Please amend the claims of the above-identified patent application as set out in **Section I (Amendments to the Claims)** hereof.

Remarks concerning the amendments to the claims and the substance of the April 18, 2008 Office Action are set out in **Section II (Remarks)** hereof.